Bashkim Ziberi

List of Publications by Year in descending order

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361413 526287 1,466 29 20 27 citations h-index g-index papers 29 29 29 840 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Ripple pattern formation on silicon surfaces by low-energy ion-beam erosion: Experiment and theory. Physical Review B, 2005, 72, .	3.2	193
2	Surface engineering with ion beams: from self-organized nanostructures to ultra-smooth surfaces. Applied Physics A: Materials Science and Processing, 2008, 91, 551-559.	2.3	145
3	Is keV ion-induced pattern formation on Si(001) caused by metal impurities?. Nanotechnology, 2010, 21, 085301.	2.6	116
4	The shape and ordering of self-organized nanostructures by ion sputtering. Nuclear Instruments & Methods in Physics Research B, 2004, 216, 9-19.	1.4	108
5	Highly ordered nanopatterns on Ge and Si surfaces by ion beam sputtering. Journal of Physics Condensed Matter, 2009, 21, 224003.	1.8	107
6	Large area smoothing of surfaces by ion bombardment: fundamentals and applications. Journal of Physics Condensed Matter, 2009, 21, 224026.	1.8	104
7	Highly ordered self-organized dot patterns on Si surfaces by low-energy ion-beam erosion. Applied Physics Letters, 2005, 87, 033113.	3.3	80
8	Ripple rotation, pattern transitions, and long range ordered dots on silicon by ion beam erosion. Applied Physics Letters, 2008, 92, .	3.3	77
9	Large area smoothing of optical surfaces by low-energy ion beams. Thin Solid Films, 2004, 459, 100-105.	1.8	67
10	Pattern transitions on Ge surfaces during low-energy ion beam erosion. Applied Physics Letters, 2006, 88, 173115.	3.3	59
11	Pattern formation on Ge by low energy ion beam erosion. New Journal of Physics, 2013, 15, 103029.	2.9	55
12	Ion beam assisted smoothing of optical surfaces. Applied Physics A: Materials Science and Processing, 2004, 78, 651-654.	2.3	52
13	Importance of ion beam parameters on self-organized pattern formation on semiconductor surfaces by ion beam erosion. Thin Solid Films, 2004, 459, 106-110.	1.8	46
14	Formation of large-area nanostructures on Si and Ge surfaces during low energy ion beam erosion. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2006, 24, 1344-1348.	2.1	41
15	Self-organized patterning on Si(001) by ion sputtering withÂsimultaneous metal incorporation. Applied Physics A: Materials Science and Processing, 2011, 102, 593-599.	2.3	33
16	Topography evolution mechanism on fused silica during low-energy ion beam sputtering. Journal of Applied Physics, 2011, 109, 043501-043501-6.	2.5	33
17	lon-induced nanopatterns on semiconductor surfaces investigated by grazing incidence x-ray scattering techniques. Journal of Physics Condensed Matter, 2009, 21, 224007.	1.8	27
18	Ion-induced self-organized dot and ripple patterns on Si surfaces. Vacuum, 2006, 81, 155-159.	3.5	26

#	Article	IF	CITATIONS
19	In situ diagnostics of zeolite crystallization by ultrasonic monitoring. Microporous and Mesoporous Materials, 2005, 80, 1-9.	4.4	21
20	Self-organized dot patterns on Si surfaces during noble gas ion beam erosion. Surface Science, 2006, 600, 3757-3761.	1.9	20
21	Ion beam sputter deposition of soft x-ray Moâ^•Si multilayer mirrors. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2005, 23, 959.	1.6	13
22	Measurement of nanopatterned surfaces by real and reciprocal space techniques. Measurement Science Review, 2010, 10 , .	1.0	11
23	Formation of two ripple modes on Si by ion erosion with simultaneous Fe incorporation. Applied Surface Science, 2011, 257, 8659-8664.	6.1	11
24	Extreme X-ray beam compression for a high-resolution table-top grazing-incidence small-angle X-ray scattering setup. Journal of Applied Crystallography, 2013, 46, 1544-1550.	4.5	7
25	GISAXS and AFM study of selfâ€assembled Fe ₂ O ₃ nanoparticles and Si nanodots. Physica Status Solidi (A) Applications and Materials Science, 2011, 208, 2619-2622.	1.8	5
26	Investigation of nucleation and phase formation of photocatalytically active TiO2 films by MePBIID. Nuclear Instruments & Methods in Physics Research B, 2009, 267, 1658-1661.	1.4	4
27	Ion Beam Sputtering: A Route for Fabrication of Highly Ordered Nanopatterns. Advanced Structured Materials, 2011, , 69-94.	0.5	4
28	Self-organized pattern formation by ion beam erosion. , 2008, , .		1
29	Importance of Internal Ion Beam Parameters on the Self-organized Pattern Formation with Low-energy Broad Beam Ion Sources. Materials Research Society Symposia Proceedings, 2009, 1181, 140.	0.1	0